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CONFIRMATION NO. 4682

| SERIAL NUMBER 10/725,827 RULE APPLICANTS Hideki Kuwajima, Kyoto, JAPAN; Hirokazu Uchiyama, Osaka, JAPAN; Yuko Ogawa, Osaka, JAPAN; *** CONTINUING DATA *** FOREIGN APPLICATIONS JAPAN 2002-351067 12/03/2002 JAPAN 2003-184163 06/27/2003 IF REQUIRED, FOREIGN FILING LICENSE GRANTED *** 03/01/2004 Foreign Priority claimed 35 USC 119 (a-d) conditions met 20 yes no 0 Met after Allowance 22 NAPAN 22 15 ADDRESS 000513 WENDEROTH, LIND & PONACK, L.L.P. 2033 K STREET N. W. SUITE 800 WASHINGTON, DC 20006-1021 | | | | | | | | | |
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| Yuko Ogawa, Ōsaka, JAPAN; "CONTINUING DATA " "FOREIGN APPLICATIONS " JAPAN 2002-351067 12/03/2002 JAPAN 2003-184163 05/27/2003 IF REQUIRED, FOREIGN FILING LICENSE GRANTED " 03/01/2004 Foreign Priority claimed so Use of the Control of the Co | Hideki Kuwajin | na, Kyoto, JAPAN; | | | | | | | |
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| 000513 WENDEROTH, LIND & PONACK, L.L.P. 2033 K STREET N. W. SUITE 800 WASHINGTON , DC 20006-1021 | Vestfled and Asknowledged COUNTRY | | | | | | CLAIMS 6 | | |
| | 000513 WENDEROTH, LIND & PONACK, L.L.P. 2033 K STREET N. W. SUITE 800 WASHINGTON , DC | | | | | | | | |
| Thin film piezoelectric element, its manufacturing method, and actuator using the same | TITLE | | | | | | | | |
| | Thin film piezoelectric e | element, its manufacturing method | 1, and actuator using the san | ne | | | | | |
| RECEIVED 1558 for following: 1.18 Fees (Issue) | RECEIVED N | o to charge/credit DEI | to charge/credit DEPOSIT ACCOUNT | | | 1.16 Fees (Filing) 1.17 Fees (Processing Ext. of time) 1.18 Fees (Issue) | | | |